

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Satoru Okamoto	Art Unit :	1792
Serial No. :	10/689,617	Examiner :	Mahmoud Dahimene
Filed :	October 22, 2003	Conf. No. :	4799
Title :	METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

NOTICE OF APPEAL

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the action dated April 22, 2008, twice rejecting claims 1-95.

The fee in the amount of \$510 for the appeal fee is being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: July 22, 2008

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